

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments	Error Definition	Errors
1	BRS	L2	24	kato-shigekazu.in.	USPA T	2001/07/26 09:36			0
2	BRS	L3	23	nishihata-kouji.in.	USPA T	2001/07/26 09:36			0
3	BRS	L4	33	tsubone-tsunehiko.in.	USPA T	2001/07/26 09:36			0
4	BRS	L5	23	itou-atsushi.in.	USPA T	2001/07/26 09:37			0
5	BRS	L6	40	2 or 3 or 4 or 5	USPA T	2001/07/26 09:37			0

	U	1	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	Retrieval Classif
1	<input type="checkbox"/>	<input type="checkbox"/>	US 6263588 B1	20010724	8	Vacuum processing apparatus and operating method therefor	34/417	34/229	
2	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6221201 B1	20010424	21	Method of holding substrate and substrate holding system	156/345	118/500 118/724 118/728 279/128 361/234	
3	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6217705 B1	20010417	21	Method of holding substrate and substrate holding system	156/345	118/500 118/728 279/128 361/234	
4	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6180019 B1	20010130	24	Plasma processing apparatus and method	216/78	118/723I 118/723R 156/345 216/80	
5	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6112431 A	20000905	8	Vacuum processing and operating method	34/406		
6	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6108929 A	20000829	8	Vacuum processing apparatus	34/92		
7	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6070341 A	20000606	8	Vacuum processing and operating method with wafers, substrates and/or semiconductors	34/406		
8	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6069096 A	20000530	24	Operating method of vacuum processing system and vacuum processing system		29/25.01 414/935 414/939	
9	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6055740 A	20000502	9	Vacuum processing apparatus and operating method therefor	34/92	34/228	
10	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6048434 A	20000411	21	Substrate holding system including an electrostatic chuck	156/345	118/500 118/724 118/728 204/298.15 204/298.31 279/128 361/234	
11	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6044576 A	20000404	7	Vacuum processing and operating method using a vacuum chamber	34/406		
12	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6028147 A	20000222	14	Block copolymer, process for producing the same and resin composition of the same	525/292	525/244 525/245 525/251 525/258 525/266 525/88 525/92R	
13	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6012235 A	20000111	9	Vacuum processing apparatus and operating method therefor	34/406		
14	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5985035 A	19991116	20	Method of holding substrate and substrate holding system	118/724	118/500 118/728 156/345 279/128 361/234	
15	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5961774 A	19991005	21	Method of holding substrate and substrate holding system	156/345	118/500 118/724 118/728 279/128 361/234	
16	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5950330 A	19990914	9	Vacuum processing apparatus and operating method therefor	34/406		
17	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5943950 A	19990831	5	Utensils for table use and cooking use	99/485	210/763 422/241 422/905 99/403 99/422 99/646R	
18	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5906684 A	19990525	21	Method of holding substrate and substrate holding system	118/728	118/500 118/724 156/345 279/128 361/234	

	Inventor	S	C	P	2	3	4	5
1	Kato, Shigekazu , et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
2	Tamura, Naoyuki , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
3	Tamura, Naoyuki , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
4	Kazumi, Hideyuki , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
5	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
6	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
7	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
8	Nishihata, Kouji , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
9	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
10	Tamura, Naoyuki , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
11	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
12	Ogawa, Atsuhisa , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
13	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
14	Tamura, Naoyuki , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
15	Tamura, Naoyuki , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
16	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
17	Taoda, Hiroko , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
18	Tamura, Naoyuki , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	Retrieval Classif
19	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5792304 A	19980811	21	Method of holding substrate and substrate holding system	156/345	118/724 118/728 279/128 361/234	
20	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5784799 A	19980728	6	Vacuum processing apparatus for substrate wafers	34/92	414/217 414/416.03 414/937 414/939 414/940	
21	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5685684 A	19971111	10	Vacuum processing system	414/217	118/719 414/416.03 414/937 414/939 414/940	
22	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5673750 A	19971007	12	Vacuum processing method and apparatus	165/275	118/724 118/725 156/345 165/80.4 165/80.5	
23	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5663884 A	19970902	13	Multiprocessing apparatus	700/121	414/935 414/939 414/940	
24	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5661913 A	19970902	7	Vacuum processing apparatus and operating method therefor	34/406	134/902	
25	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5562820 A	19961008	6	Process for purifying water	210/94	210/205 210/251 422/186.3 422/241	
26	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5553396 A	19960910	6	Vacuum processing apparatus and operating method therefor	34/406	134/902 34/92 414/222.13	
27	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5457896 A	19951017		Vacuum processing apparatus and operating method therefor	34/406	34/92	
28	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5449467 A	19950912		Process for purifying water	210/748	210/763 210/908 210/910	
29	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5448470 A	19950905		Multiprocessing apparatus	700/2	700/214	
30	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5445484 A	19950829		Vacuum processing system	414/217	118/719 414/416.03 414/937 414/939 414/940	
31	<input type="checkbox"/>	<input type="checkbox"/>	US 5349762 A	19940927	9	Vacuum processing apparatus and operating method therefor	34/406	34/92	
32	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5320982 A	19940614	9	Wafer cooling method and apparatus	438/714	118/724 156/345 279/128 361/233 438/715	
33	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5314509 A	19940524	7	Vacuum processing apparatus and operating method therefor	34/406	134/902 34/92	
34	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5105173 A	19920414	18	Band-pass filter using microstrip lines	333/204	333/203 333/205	
35	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5085750 A	19920204	9	Plasma treating method and apparatus therefor	204/192.32	118/723R 118/724 118/725 156/345 204/298.09 204/298.33 204/298.38 216/67	
36	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5078851 A	19920107	9	Low-temperature plasma processor	204/298.34	118/723R 118/724 118/725 156/345 204/298.31 204/298.38	

	Inventor	S	C	P	2	3	4	5
19	Tamura, Naoyuki , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
20	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
21	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
22	Tsubone, Tsunehiko , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
23	Nishihata, Kouji , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
24	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
25	Taoda, Hiroshi , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
26	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
27	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
28	Taoda, Hiroshi , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
29	Nishihata, Kouji , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
30	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
31	Kato, Shigekazu , et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
32	Tsubone, Tsunehiko , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
33	Kato, Shigekazu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
34	Itou, Atsushi	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
35	Soraoka, Minolu , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
36	Nishihata, Kouji , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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37	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4911812 A	19900327	8	Plasma treating method and apparatus therefor	204/192.32	118/723E ; 118/723MR ; 118/723MW ; 118/724 ; 156/345 ; 204/298.09 ; 204/298.31 ; 216/67 ; 422/186.05 ; 427/575	
38	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4824309 A	19890425	12	Vacuum processing unit and apparatus	414/217	118/50 ; 414/222.13 ; 414/939	
39	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4565601 A	19860121	14	Method and apparatus for controlling sample temperature	216/59	156/345 ; 204/192.32 ; 204/298.09 ; 204/298.31 ; 204/298.32 ; 216/71	
40	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4527698 A	19850709	16	Method of and apparatus for supporting rope of crane having articulating structure	212/299	212/262	

	Inventor	S	C	P	2	3	4	5
37	Kudo, Katsuyoshi , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
38	Kakehi, Yutaka , et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
39	Kakehi, Yutaka , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
40	Nishihata, Kouji , et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>